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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/743,272	. 12/23/2003	Joost Jeroen Ottens	081468-0306369	4455	
P.O. BOX 1050	PILLSBURY WINTHROP SHAW PITTMAN, LLP P.O. BOX 10500			YOUNG, CHRISTOPHER G	
MCLEAN, VA	J, VA 22102		ART UNIT	PAPER NUMBER	
	,		1756		
SHORTENED STATUTORY	Y PERIOD OF RESPONSE	MAIL DATE	DELIVERY MODE		
3 MON	NTHS	12/20/2006	PAPER		

Please find below and/or attached an Office communication concerning this application or proceeding.

If NO period for reply is specified above, the maximum statutory period will apply and will expire 6 MONTHS from the mailing date of this communication.

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	Application No.	Applicant(s)				
	10/743,272	OTTENS ET AL.				
Office Action Summary	Examiner	Art Unit	-			
	Christopher G. Young	1756				
The MAILING DATE of this communication app Period for Reply	pears on the cover sheet with the c	correspondence address				
A SHORTENED STATUTORY PERIOD FOR REPL WHICHEVER IS LONGER, FROM THE MAILING D.  - Extensions of time may be available under the provisions of 37 CFR 1.1 after SIX (6) MONTHS from the mailing date of this communication.  - If NO period for reply is specified above, the maximum statutory period - Failure to reply within the set or extended period for reply will, by statute Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION (36(a). In no event, however, may a reply be tin will apply and will expire SIX (6) MONTHS from (6), cause the application to become ABANDONE	N. nely filed the mailing date of this communication (35 U.S.C. § 133).				
Status						
1)⊠ Responsive to communication(s) filed on <u>03 N</u>	lovember 2006.					
2a) ☐ This action is <b>FINAL</b> . 2b) ☑ This	action is non-final.					
3) Since this application is in condition for allowa	☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is					
closed in accordance with the practice under E	Ex parte Quayle, 1935 C.D. 11, 45	53 O.G. 213.				
Disposition of Claims						
4) ☐ Claim(s) 1-50.is/are pending in the application 4a) Of the above claim(s) 35-50 is/are withdray 5) ☐ Claim(s) 6-16,18-23,25-27 and 31-34 is/are all 6) ☐ Claim(s) 1-5,17,24 and 28-30 is/are rejected. 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/o	vn from consideration. lowed.					
Application Papers	•					
9) The specification is objected to by the Examine 10) The drawing(s) filed on 23 December 2003 is/a Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Ex	re: a)⊠ accepted or b)⊡ object drawing(s) be held in abeyance. See tion is required if the drawing(s) is ob	e 37 CFR 1.85(a). jected to. See 37 CFR 1.121(d	)).			
Priority under 35 U.S.C. § 119		•				
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of:  1. Certified copies of the priority document 2. Certified copies of the priority document 3. Copies of the certified copies of the priority application from the International Bureau * See the attached detailed Office action for a list	s have been received. s have been received in Applicati rity documents have been receive u (PCT Rule 17.2(a)).	on No ed in this National Stage				
Attachment(s)						
1) Notice of References Cited (PTO-892)	4) Interview Summary					
<ul> <li>Notice of Draftsperson's Patent Drawing Review (PTO-948)</li> <li>Information Disclosure Statement(s) (PTO/SB/08)</li> <li>Paper No(s)/Mail Date <u>2 sheets</u>.</li> </ul>	Paper No(s)/Mail Da 5) Notice of Informal P 6) Other:					

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#### **DETAILED ACTION**

### Election/Restrictions

- 1. Applicant's election without traverse of claims 1-34 in the reply filed on November
- 3, 2006 is acknowledged.
- 2. Claims 35-50 stand withdrawn as being part of the non-elected invention.

## Claim Rejections - 35 USC § 102

3. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 4. Claims 1-3 and 28-30 are rejected under 35 U.S.C. 102(b) as being anticipated by Publication Number 04192317 (Nei Masahiro).

A careful review of the abstract and constitution of the foreign document clearly shows the claimed embodiments of 1-3 and 28-30, that being a method of correcting thermally-induced field deformations of a lithographically exposed substrate, comprising: exposing a pattern onto a plurality of fields of a substrate in accordance with pre-specified exposure information; measuring attributes of said fields to assess deformation of said fields induced by thermal effects of said exposing; determining corrective information based on said measured attributes; and adjusting said pre-

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specified exposure information, based on said corrective information, to compensate for the thermally-induced field deformations.

5. Claims 1-5, 17 and 28-30 are rejected under 35 U.S.C. 102(b) as being anticipated by EP 0877297.

A careful review of the foreign document clearly shows the claimed embodiments of 1-5, 17 and 28-30, that being a method of correcting thermally-induced field deformations of a lithographically exposed substrate, comprising: exposing a pattern onto a plurality of fields of a substrate in accordance with pre-specified exposure information; measuring attributes of said fields to assess deformation of said fields induced by thermal effects of said exposing; determining corrective information based on said measured attributes; and adjusting said pre-specified exposure information, based on said corrective information, to compensate for the thermally-induced field deformations. See specifically the Abstract on the first page, and the claims on page 8.

6. Claims 1-5, 17, 24 and 28-30 are rejected under 35 U.S.C. 102(b) as being anticipated by Okino et al., US Patent Number 6,447,964.

A careful review of the patent clearly shows the claimed embodiments of 1-5, 17, 24 and 28-30, that being a method of correcting thermally-induced field deformations of a lithographically exposed substrate, comprising: exposing a pattern onto a plurality of fields of a substrate in accordance with pre-specified exposure information; measuring attributes of said fields to assess deformation of said fields induced by thermal effects of

said exposing; determining corrective information based on said measured attributes; and adjusting said pre-specified exposure information, based on said corrective information, to compensate for the thermally-induced field deformations.

Methods are disclosed in the patent for reducing effects of thermal expansion of a sensitive substrate arising during microlithographic exposure of the substrate using a charged particle beam. Thermal expansion ordinarily causes lateral shift of exposure position of dies (chips) on the substrate which tends to reduce the positional accuracy with which images of the dies are formed on the substrate. Generally, regions of the substrate where entire dies are formed are exposed first, followed by regions (especially peripheral regions) exposed with only portions of dies. Refer particularly to the Abstract and claims 1-16.

### Allowable Subject Matter

7. Claims 6-16, 18-23, 25-27 and 31-34 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

#### Conclusion

8. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Christopher G. Young whose telephone number is 571-272-1394. The examiner can normally be reached on Monday-Friday.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Mark Huff can be reached on 571-272-1385. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

Christopher G./Young

Primary Examiner

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